

Methods, FMF, Fiederle

<p>Technology Lab</p> <p><i>Clean Room Facility</i></p>	<p>Model: -- Unit and Room: <i>FMF, Physics Hall</i> Responsible: Further information:</p>	
<p>Short Description:</p> <p>Full equipped clean room facility for processing</p>	<p>Picture of the Equipment</p>	
<p>Available Experiments/Techniques:</p> <p>Mask aligner Surface profiler Optical microscope Plasma Ion Etcher Electron Gun Sputtering facility Flip-chip bonder Reflow furnace</p>		
<p>Special Equipment:</p> <p>Processing of samples and devices for deposition of metals and passivation Processing of micrometer structures down to 1 μm precision</p>		
<p>Measurements on the equipment are currently done by:</p>	<p><input type="checkbox"/> Students <input type="checkbox"/> Students after Introduction <input checked="" type="checkbox"/> Students after extensive training <input checked="" type="checkbox"/> Trained scientific service personal</p>	
<p>Recent Publications, where this instrument was important (optional): Give citation</p>		
<p>Typical problems that may be solved with this instrument:</p>	<ul style="list-style-type: none"> - <i>Processing of device structures</i> - <i>Development of metallization and passivation</i> 	